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Application ID:

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Title of Invention:

ELECTRO CHEMICAL

MECHANICAL POLISHING AND

ENDPOINT DETECTION FOR

ELECTROPOLISHING PROCESSES

First Named Inventor:

Alain Duboust

Domestic/Foreign Application:

Domestic Application

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PATEN Electronic Version v1.1
Stylesheet Version v1.1.0

Title of Invention

ENDPOINT DETECTION FOR ELECTRO CHEMICAL MECHANICAL POLISHING AND ELECTROPOLISHING PROCESSES

Application Number:

10/056316

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Alain Duboust

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Documents being submitted

Files

us-ids

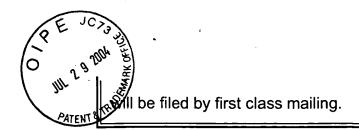
APPM6339-usidst.xml

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Comments

An additional Information Disclosure Statement citing foreign and articles references



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ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Sectronic Version v18 Stylesheet Version v18.0

Title of Invention

ENDPOINT DETECTION FOR ELECTRO CHEMICAL MECHANICAL POLISHING AND ELECTROPOLISHING PROCESSES

Application Number:

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Alain Duboust

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Art Unit:

1745

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Thomas Parsons

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(3162588 or 3448023 or 3873512 or 4125444 or 4713149 or 4839993 or 4954141 or 4956056 or 5096550 or 5136817 or 5578362 or 5624300 or 5738574 or 5804507 or 5871392 or 5893796 or 5931719 or 5938801 or 6001008 or 6004880 or 6010395 or 6017265 or 6020264 or 6024630 or 6090239 or 6116998 or 6153043 or 6156124 or 6159079 or 6171467 or 6210257 or 6238271 or 6244935 or 6273798 or 6297159 or 6328872 or 6368184 or 6381169 or 6386956 or 6402591 or 6406363 or 6409904 or 6413388 or 6413403 or 6471847 or 6482307 or 6497800 or 6630059

or 20010005667 or 20010024878 or

20010035354 or 20010040100 or 20020008036

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20020070126 or 20020077037 or 20020088715

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20030114087 or 20030116445 or 20030116446

or 20030213703 or 20030016446 or

20020119286 or 20020130049 or 20030116445

or 20030213703 or 20030114087).pn.

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Note: Applicant is not required to submit a paper copy of cited US Patent Documents

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Note: Applicant is not required to submit a paper copy of cited US Published Applications

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